

In the Specification:

Please replace paragraph 0023 on pages 7-8 with the following rewritten paragraph:

Paragraph [0023]:

5 Probe assembly 100 of Figure 1 also includes mask 130 which
includes apertures 135 therein. Apertures 135 are of a size
which is comparable to that of the outer diameter of probe wire
200 so that aperture 135 provides a guide for motion of probe
wires 200 as probe wire tips 201 (see Figures 2 and 3) are urged
10 against the wafer pads. Mask 130 is substantially flat, as is
base 110. Mask 130 is disposed at a substantially fixed distance
from base 110 by means of sidewall support or supports 120.
Support 120 comprises any convenient feature, mechanism or means
for supporting mask 130 at a substantially fixed distance from
15 base 110. Sidewall support 120 preferably comprises material
selected from the following group: ceramic, plastic, composite or
metal. The most important quality for selecting a material for
sidewall support 120 is its dimensional stability over time and
use. In preferred embodiments of the present invention sidewall
20 120 comprises a foam material. While sidewall support 120 may
comprise physically distinct and separate parts, it is preferred
that it be formed as an integral unit. Such a structure is meant
to provide dimensional stability and constancy in terms of the
overall height of probe assembly 100. Uniformity in height helps
25 to assure corresponding uniformity in applied contact force. In
this regard, it is recalled from above that controlled contact
force is a desirable aspect of the present invention: too much
force damages the wafer pads and too little force fails to
produce a desirably low and consistent contact resistance.